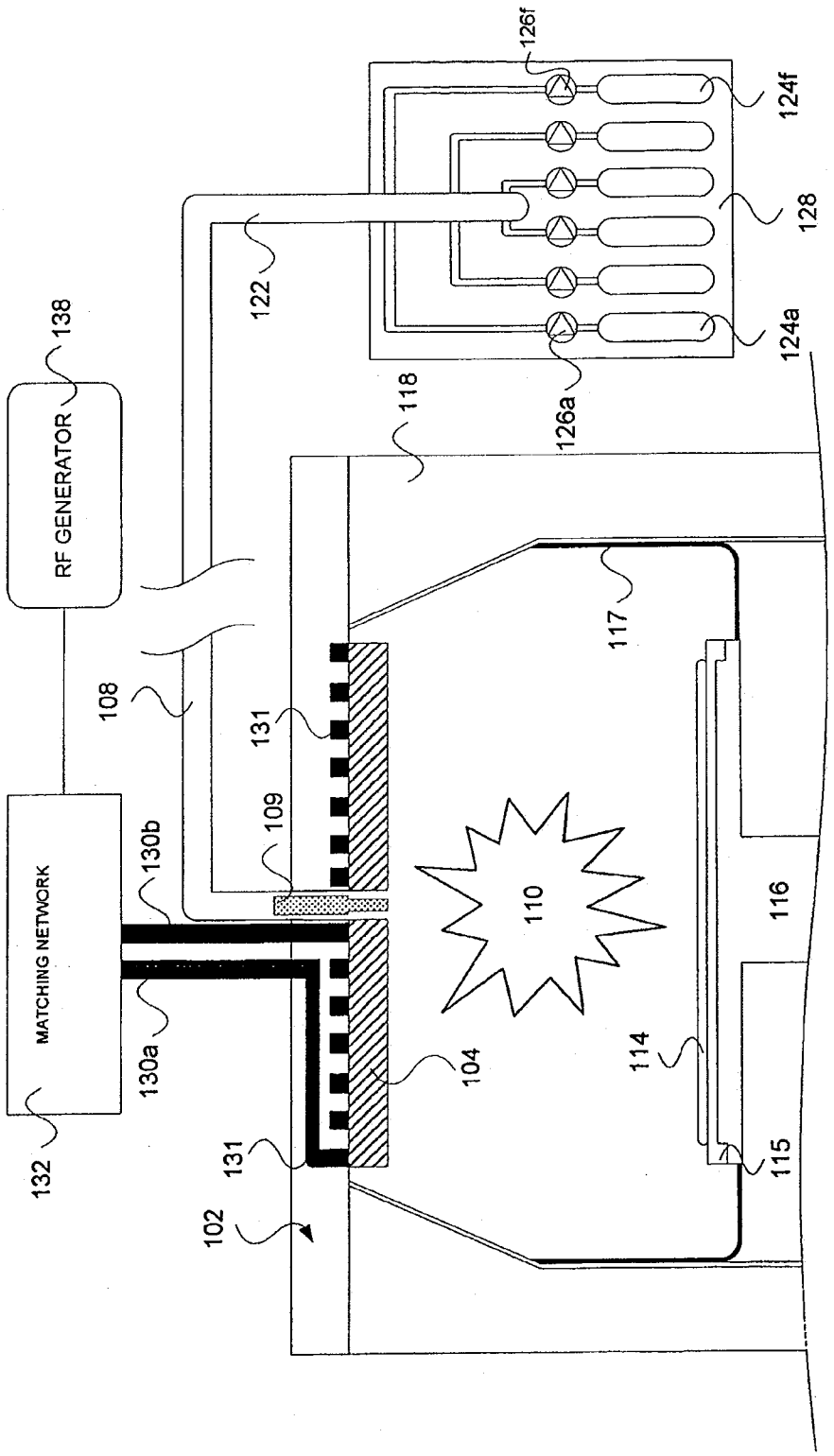

126f
124f
128
122
138
RF GENERATOR
124a
118
126a
108
131
117
109
130b
110
116
MATCHING NETWORK
130a
104
114
131
115
132
102

FIG. 1

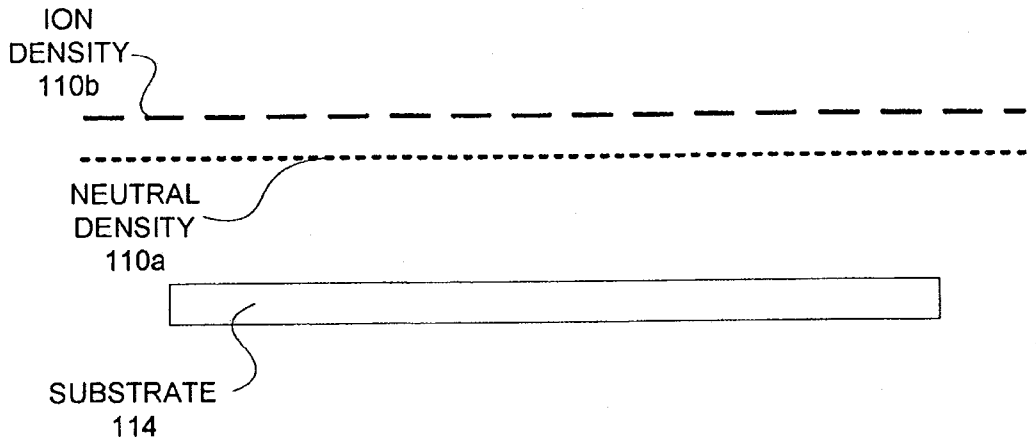

ION
DENSITY
110b
NEUTRAL
DENSITY
110a
SUBSTRATE
114

FIG. 2A

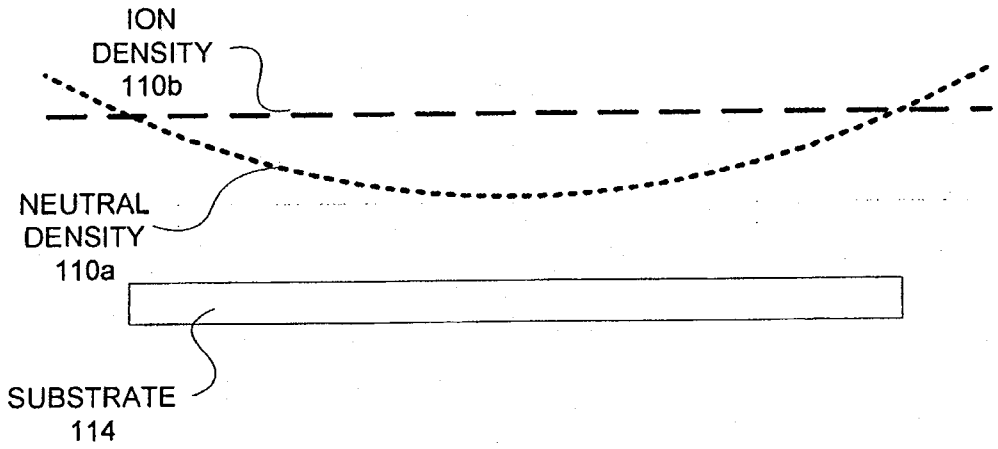

ION
DENSITY
110b
NEUTRAL
DENSITY
110a
SUBSTRATE
114

FIG. 2B

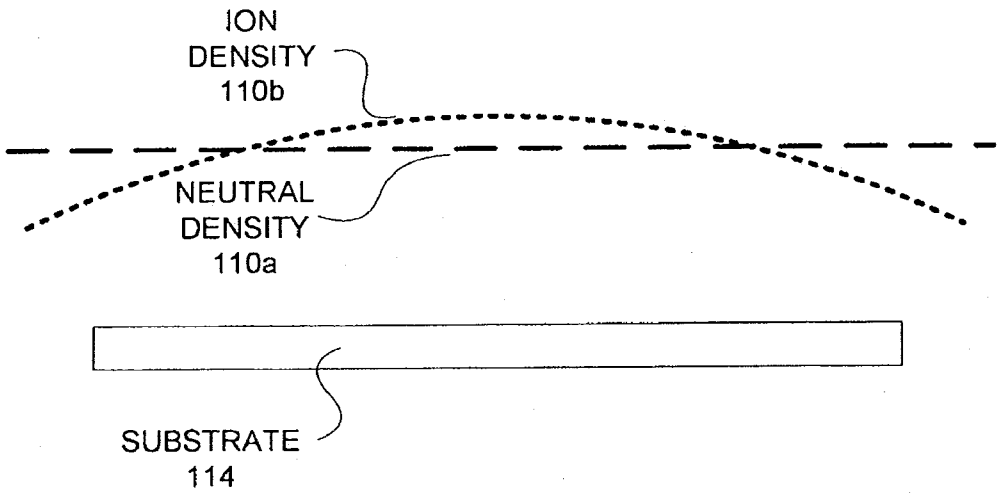
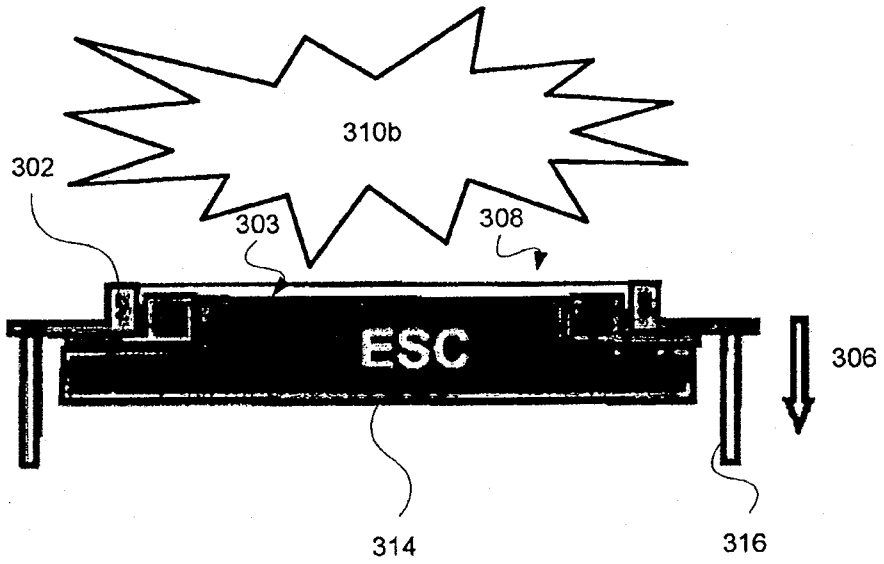


FIG. 2C


310b
302
303
308
ESC
306
314
316

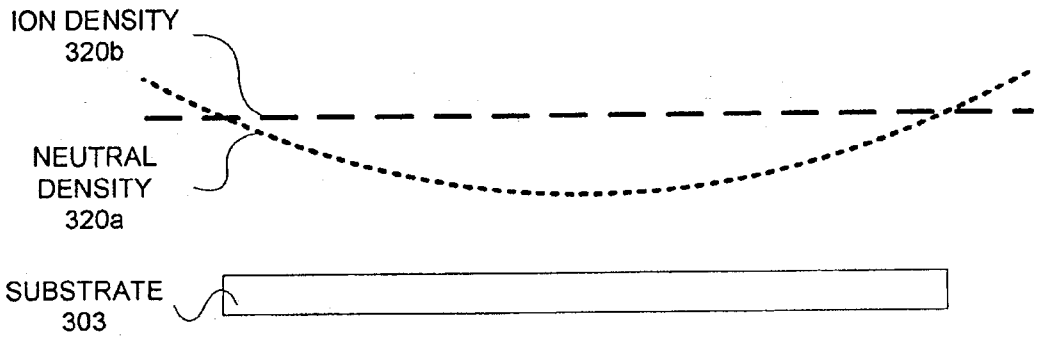
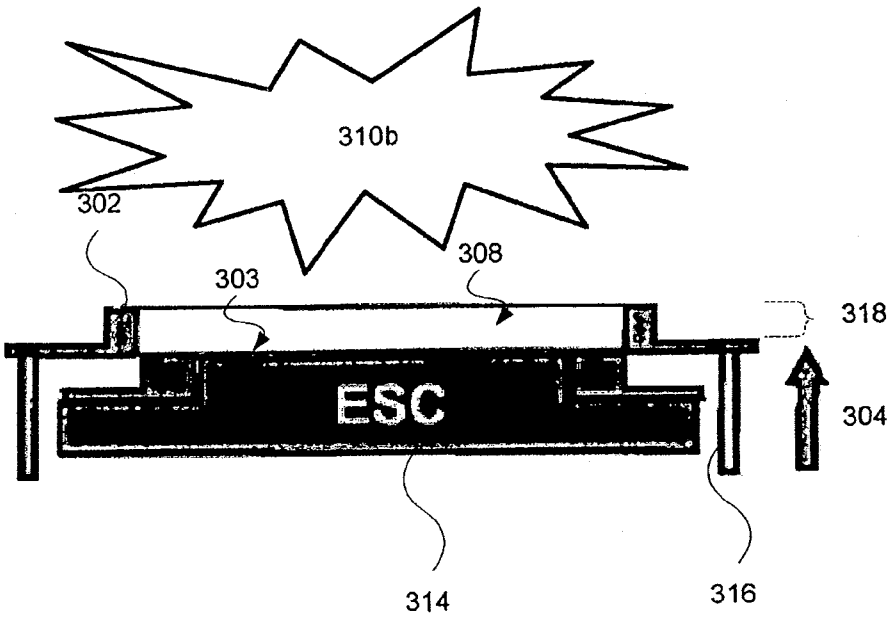

ION DENSITY
320b
NEUTRAL
DENSITY
320a
SUBSTRATE
303

FIG. 3A


310b
302
308
303
318
ESC
304
314
316

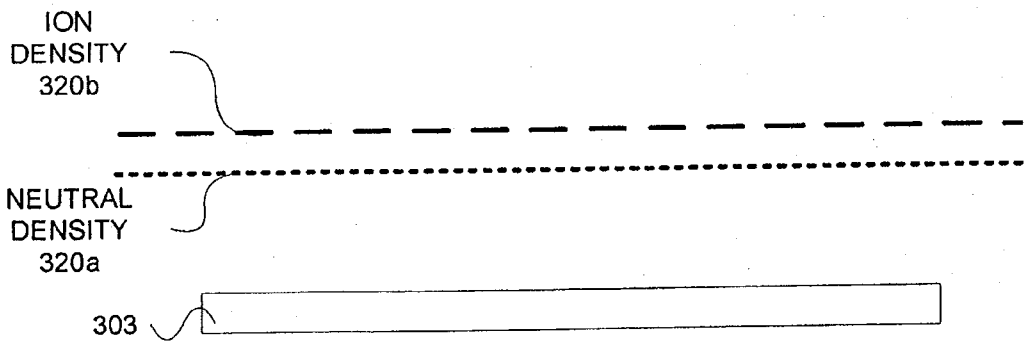

ION
DENSITY
320b
NEUTRAL
DENSITY
320a
303

FIG. 3B

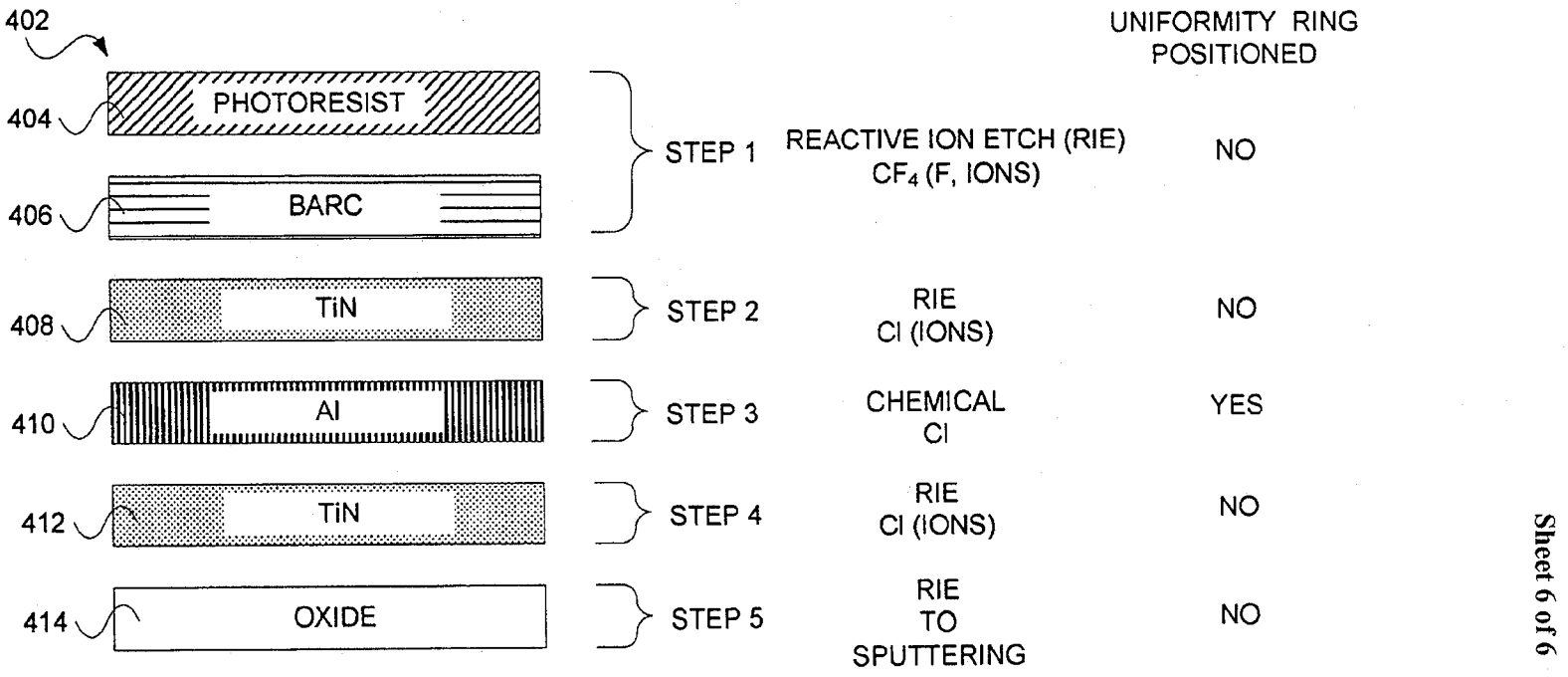

402
404
PHOTORESIST
406
BARC
408
TiN
410
Al
412
TiN
414
OXIDE
STEP 1
STEP 2
STEP 3
STEP 4
STEP 5
REACTIVE ION ETCH (RIE)
CF4 (F, IONS)
RIE
Cl (IONS)
CHEMICAL
Cl
RIE
Cl (IONS)
RIE
TO
SPUTTERING
UNIFORMITY RING
POSITIONED
NO
NO
YES
NO
NO

FIG. 4